

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: Hans Wilfried Peter KOOPS  
Klaus EDINGER

Title: **PROCEDURE FOR ETCHING OF MATERIALS AT THE SURFACE  
WITH FOCUSSED ELECTRON BEAM INDUCED CHEMICAL  
REACTION AT SAID SURFACE**

Application Serial No. : 10/628,174

Filing Date: July 28, 2003

Assignee: NaWoTec GmbH

Priority claimed: October 16, 2002, European Patent No. 02 023 217.9

Docket: 8183

Examiner: Allan Olsen, Art Unit 1792

Date: July 29, 2008

Confirmation No. 5591

**AFTER-FINAL AMENDMENT AND INTERVIEW SUMMARY RECORD**

This amendment is in response to the Advisory Office Action mailed July 16, 2008. Please cancel claims 42 and 44. Please amend claims 45, 46, 49, 63, 64, 65, and 68. Claims 1-44 are now canceled.

Claims 45-68 are in the application. Applicant wishes to thank the Primary Examiner for the determination of allowable subject matter in regard to claims 45-68. This amendment addresses Section 112 issues discussed and agreed upon in the interview conducted by telephone today, July 29, 2008. This amendment puts the application in a

condition for allowance.

The filing of this After-Final Amendment is believed to be timely. However, if the Patent Office determines that an Extension of Time is necessary, then please consider this as a conditional petition for an extension of time and please charge our deposit account 23-3060 accordingly. If there are any additional charges, or any overpayment, in connection with the filing of this after-final amendment, the Commissioner is hereby authorized to charge any such deficiency, or credit any such overpayment, to Deposit Account 23-3060.

Respectfully submitted,

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